



IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

APPLN. OF: FOTLAND et al.

SERIAL NO.: 09/299,388

FILED: April 27, 1999

FOR: METHOD FOR DEPOSITING PARTICLES ONTO A SUBSTRATE ...

GROUP: 1619

EXAMINER: FRANK I. CHOI

DOCKET: MICRODOSE 99.01 CON

Assistant Commissioner for Patents
Washington, D.C. 20231

4619 #230
9/25/02
RECEIVED

SEP 19 2002

TECH CENTER 1600/2900

AMENDMENT E

Dear Sir:

This Amendment is being filed in response to the Official Action mailed June 14, 2002.

Please amend the Application as follows:

IN THE CLAIMS:

Please amend claims 1, 32-34, 48, 52-57, 60, 63, 64, 66, 67 and 69-71 to read as follows:

1. (Thrice Amended) A method for depositing particles onto a dielectric substrate comprising the steps of forming an aerosol of said particles in a first region; transporting the resulting aerosol to a second region, and applying a charge on said aerosol particles in said second region, positioning said charged aerosol particles with essentially a zero velocity in a deposition zone located in said second region proximate to said dielectric substrate, and applying an alternating electric field formed in said deposition zone between a first electrode positioned in said second region and a second electrode positioned underlying and in contact with said dielectric substrate whereby to drive said charged particles from the aerosol and deposit said

HAYES SOLOWAY P.C.
130 W. CUSHING ST.
TUCSON, AZ 85701
TEL. 520.882.7623
FAX. 520.882.7643

175 CANAL STREET
MANCHESTER, NH 03101

TEL. 603.668.1400

FAX. 603.668.8566

09/18/2002 WABDELRI 00000073 09299388

01 FT:102

84.00 OP